

# Lecture SCT2 - Process Integration

## 6. Web-based virtual Lecture: May 20 2021 Prof. Dr. Johann W. Bartha

Inst. f. Halbleiter und Mikrosystemtechnik  
Technische Universität Dresden

Summer Semester 2021

Start lecture here



"SCT\_SS21\_06.1" 05:00

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## Review:

- SC-Basics
- DRAM Device
- POLYCID
- RIE
- MOS Capacitor
- Feld/Gate Oxide
- EOT
- MOS-Cap-CV ..

## Today: MOSFET +

0. Introduction/ Lab organization/DMA /SCT1/Motivation
1. Process integration
  - 1.MOS Structure, MOS Capacitor
  - 2.Structure of a MOSFET
  - 3.I/V behaviour
2. Circuits in Metal-Gate FET Technology
  - 1.Process sequence of N-MOSFET in Metal Gate
  - 2.From inverter to memory cell
  - 3.SRAM in NMOS Metal Gate
  - 4.The threshold voltage of the MOSFET
    - 1.Parasitic FET
    - 2.Enhancement/Depletion Transistor
    - 3.N-MOS Logic by E/D Transistors
    - 4.Process sequence of the N-MOS E/D Process
3. Self aligned Process
  - 1.Metal Gate -> Si Gate
  2. Channel-Stop & LOCOS Technology
    - 1.Example: Process flow of E/D SiGate LOCOS Inverter
    - 2.LOCOS Variation
    - 3.Shallow Trench Isolation
  - 3.Lightly doped drain
  - 4.SALICIDE
  5. Self Aligned Contacts (SAC)
  6. Resist trimming
- 4.Transition to CMOS Technology
  - 1.MOS Transistor Types
  - 2.CMOS Inverter
    - 1.Consideration NMOS E/D Inverter
    - 2.Comparison CMOS Inverter
  - 3.CMOS Process flow (Example CMOS 180 nm process)
5. Further Considerations
  1. Scaling
    1. Challenges
    - 2.Material Equivalent Scaling
    - 3.Further Concepts

SC-  
Basics

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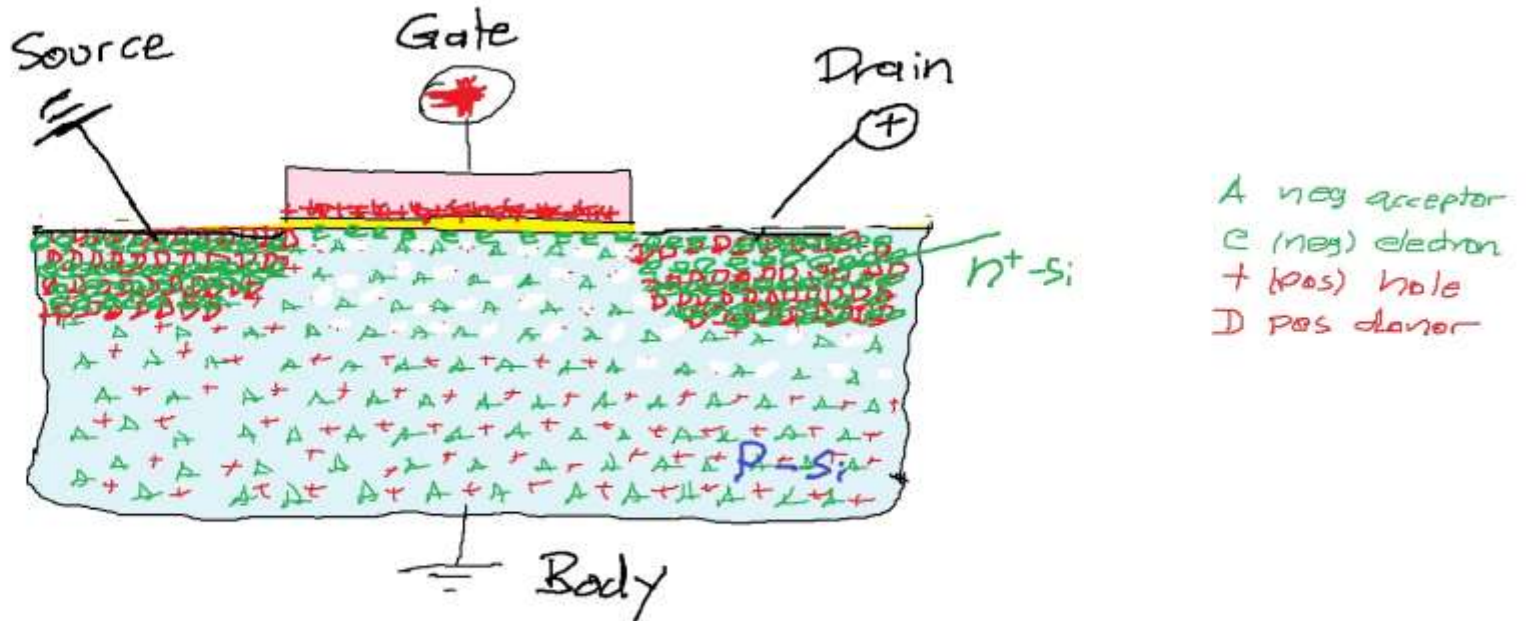
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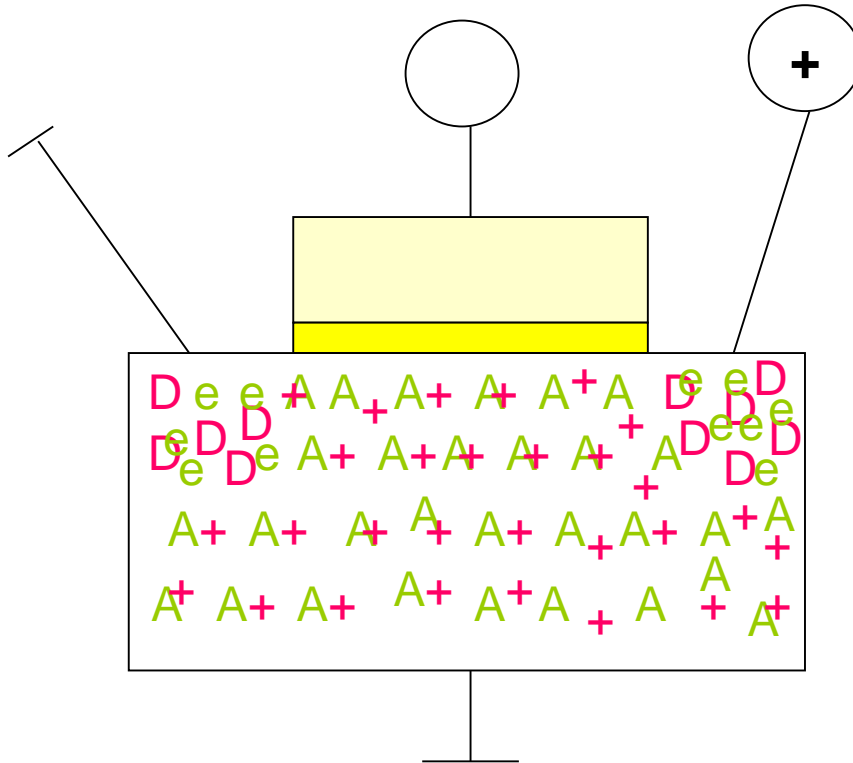
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SC-  
Basics

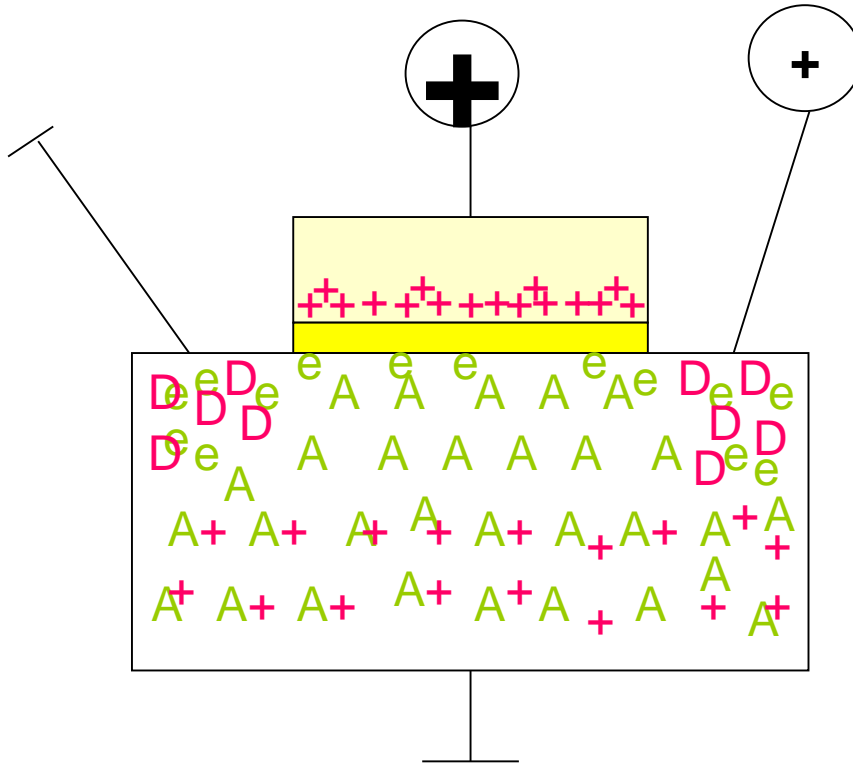


Current can not flow!

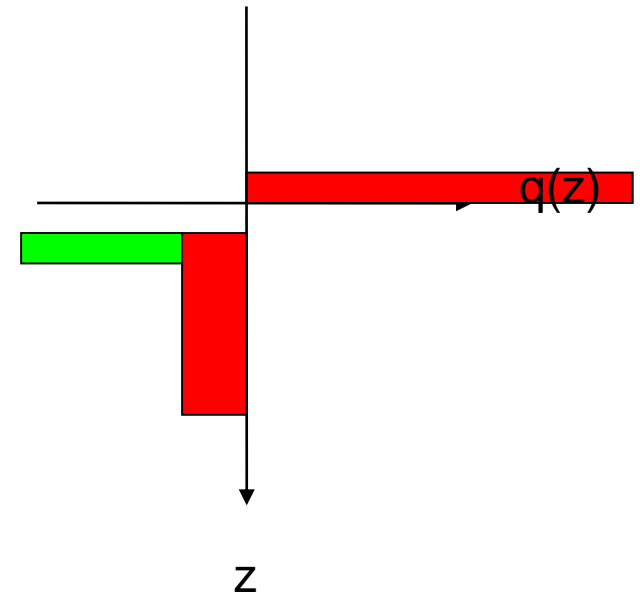


D = pos. charged donor  
 A = neg. charged acceptor  
 + = pos. charge (hole)  
 e = neg. charge (electron)

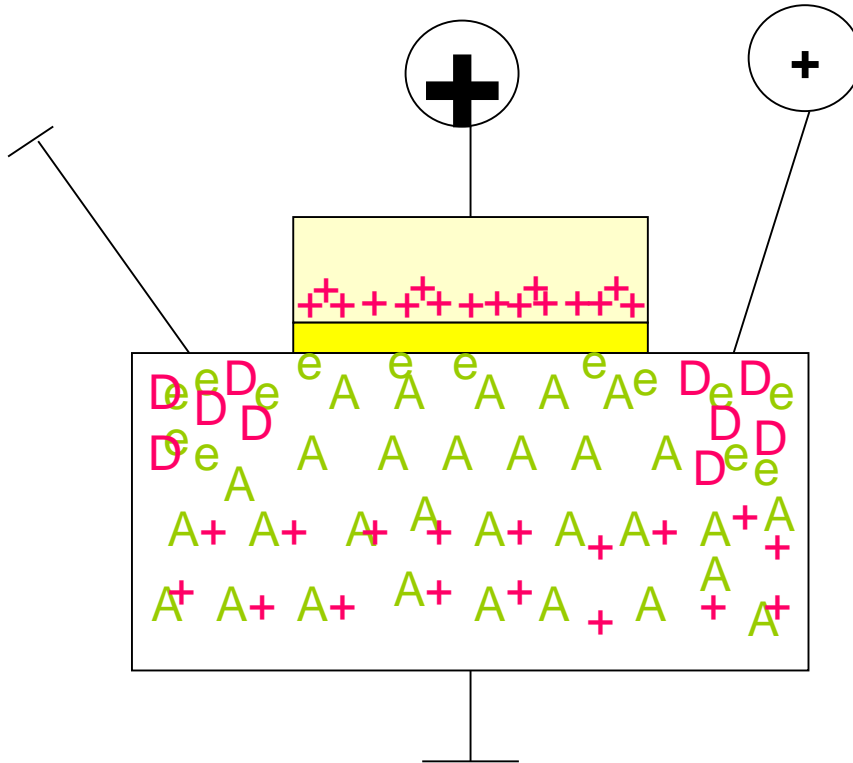
Current can flow!



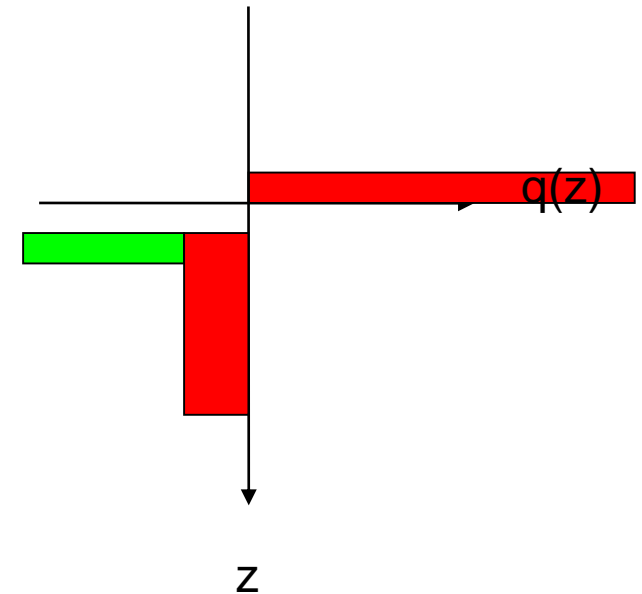
Inversion



Current can flow!



Inversion



Continue 

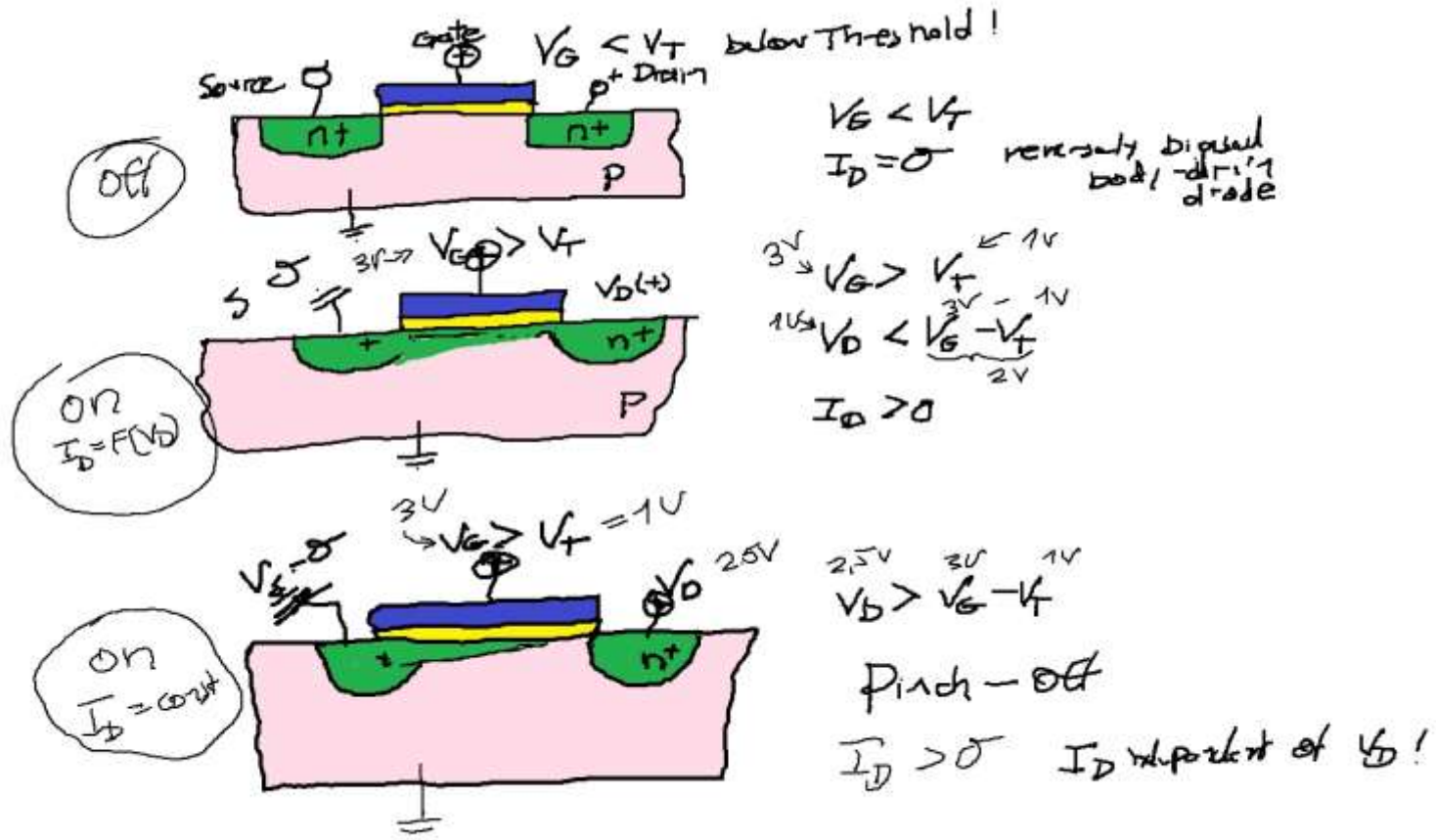
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Blackboard



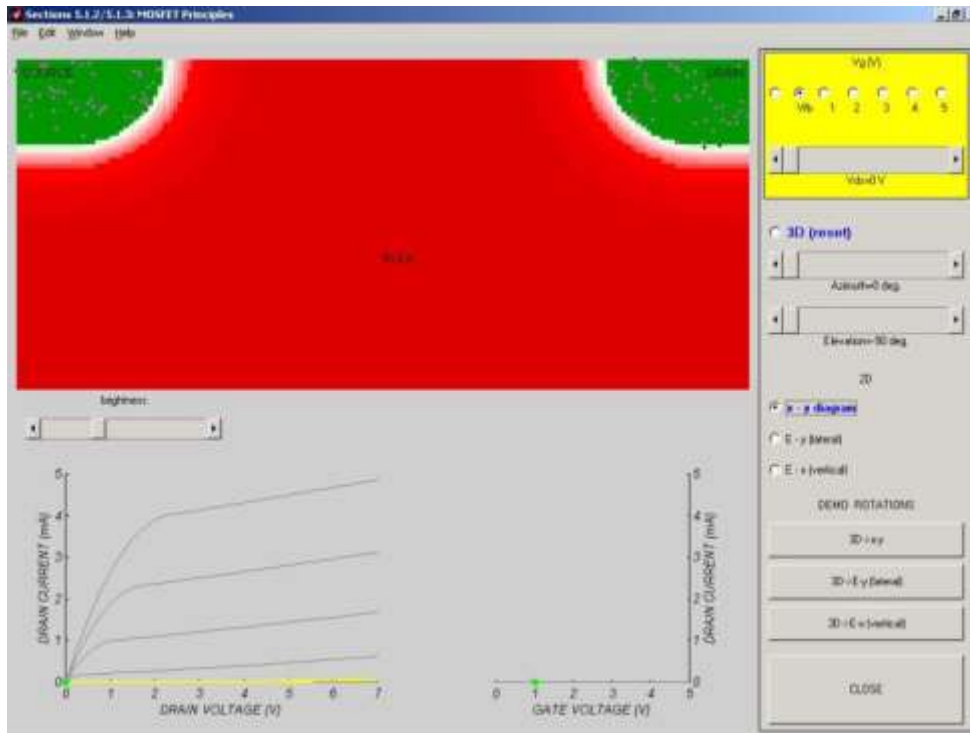
# Blackboard



## The MOS FET

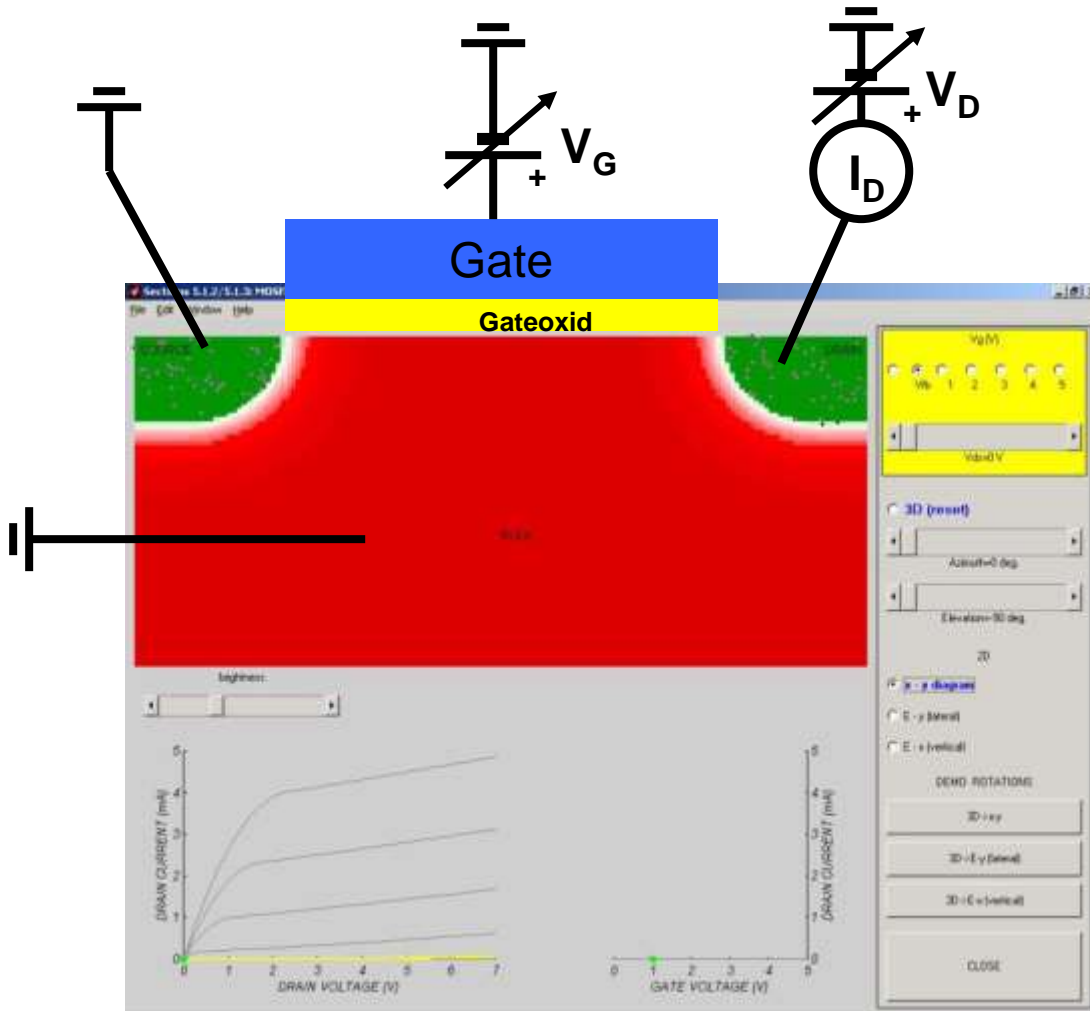
Terms:

- accumulation
- depletion
- inversion
- threshold voltage
- pinch off
- saturation current
- triode mode



Sima Dimitrijević, Understanding Semiconductor Devices, Oxford University Press 2000

Start:  
FETsimE  
.pdf



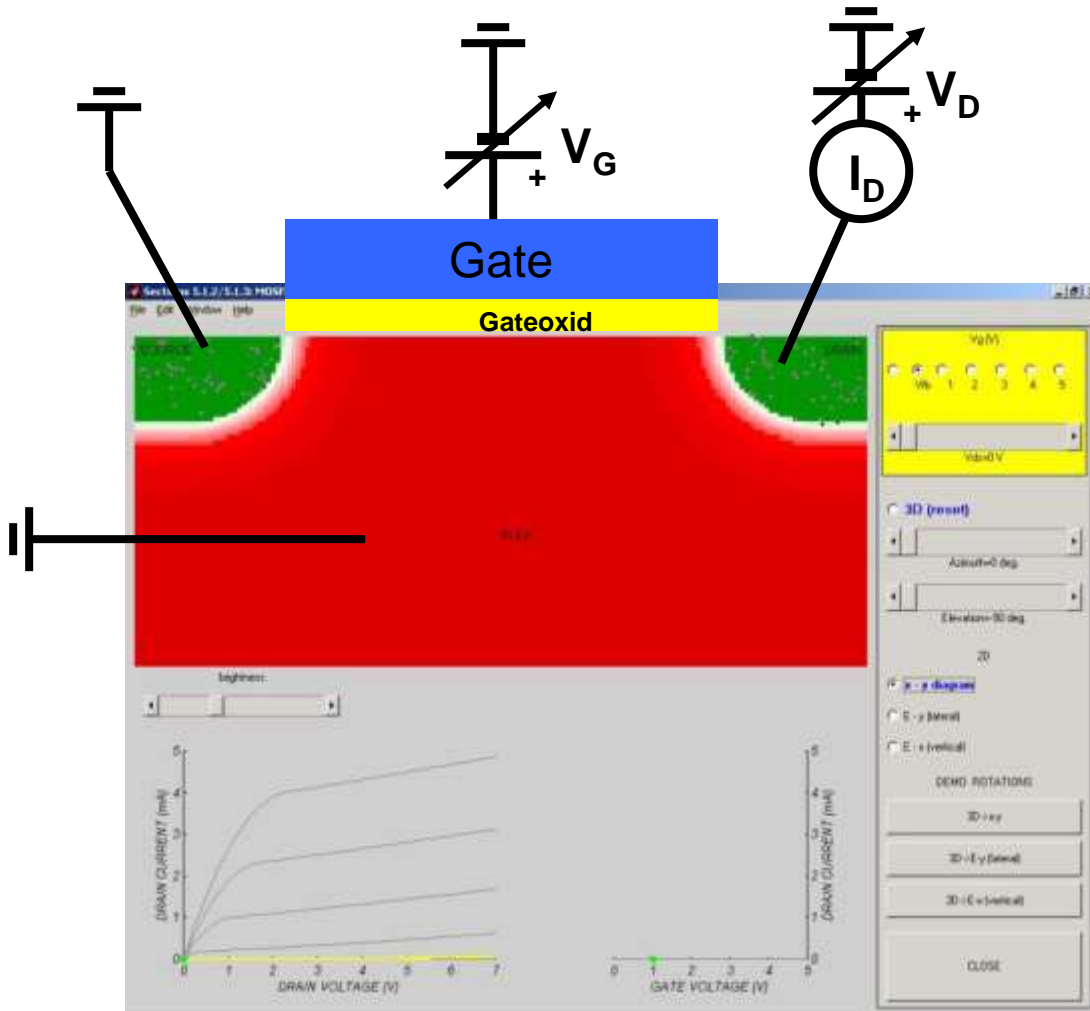
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Start:  
 FETsimE  
 .pdf



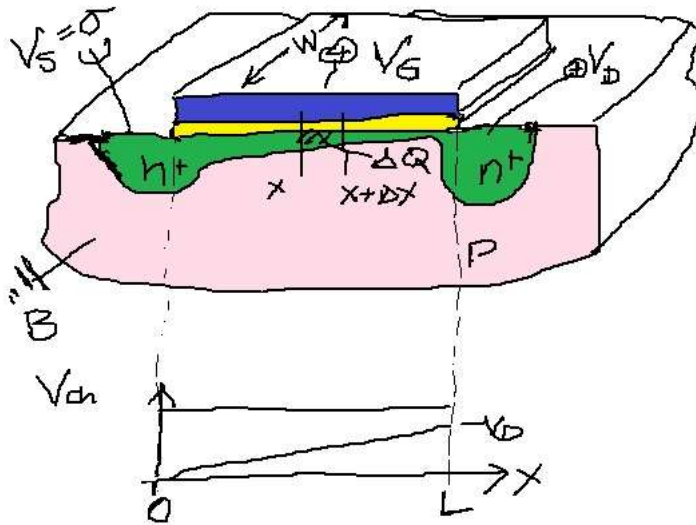
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## The MOS FET

Terms:

- accumulation
- depletion
- inversion
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- saturation current
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Start:  
 FETsimE  
 .pdf



- Gate capacity  $C_G = \frac{\epsilon_0 \epsilon_f \cdot W \cdot L}{d_{ox}}$

- Capacity over  $\Delta x$   $\Delta C = C_G \frac{\Delta x}{L}$

- Charge within  $\Delta x$

$$\Delta Q = \Delta C (V_G - V(x))$$

- El. Field in  $x$   $E = -\frac{dV}{dx}$

- Velocity of  $e$  in the channel

$$v = -\mu E = \mu \frac{dV}{dx} \quad (\mu \hat{=} \text{mobility})$$

- carrier density per length

$$S_x = \frac{\Delta Q}{\Delta x}$$

$$\text{Current } I_D = S_x v = \frac{\Delta Q}{\Delta x} \mu \frac{dV}{dx} = \frac{\Delta C (V_G - V(x))}{\Delta x} \mu \frac{dV}{dx}$$

$$I_D = \frac{C_G \Delta x (V_G - V(x))}{L \Delta x} \mu \frac{dV}{dx} = \frac{C_G \mu}{L} (V_G - V(x)) \frac{dV}{dx}$$

$$I_D \int_0^L dx = \frac{C_G \mu}{L} \int_0^{V_D} (V_G - V(x)) dV = \frac{C_G \mu}{L} \left( \int_0^{V_D} V_G dV - \int_0^{V_D} V dV \right)$$

$$I_D L = \frac{C_G \mu}{L} \left( V_G V_D - \frac{1}{2} V_D^2 \right) = \frac{C_G \mu}{L} \left( V_G V_D - \frac{1}{2} V_D^2 \right)$$

So far  $\tau$  is not considered

To correct  $V_G \rightarrow V_G - V_t$

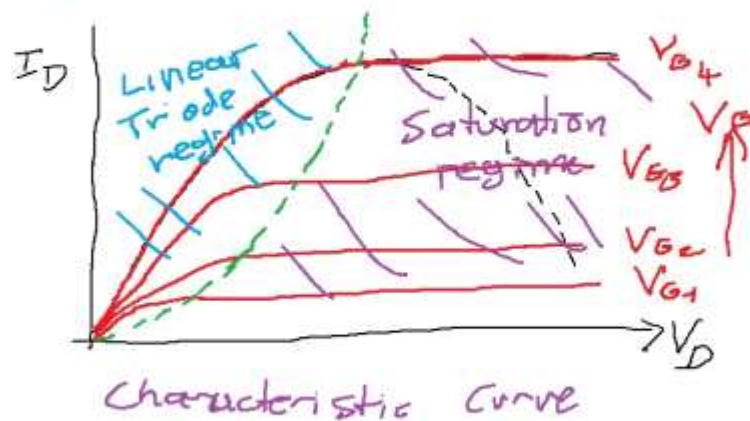
$$I_D = \frac{\mu \epsilon_f \epsilon_0 W}{d_{ox} L} \left[ (V_G - V_t) V_D - \frac{1}{2} V_D^2 \right]$$



$$\text{Max } I_D'(V_D) = 0 \quad (V_G - V_T) - V_D = 0$$

Max at  $V_D = (V_G - V_T)$  Pinch off condition

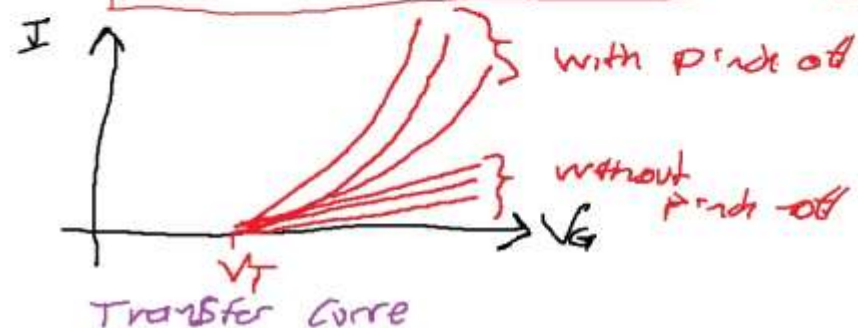
$$I_D = \frac{\mu E_0 E_f}{d_{ox}} \frac{W}{L} \left\{ (V_G - V_T) \cdot V_D - \frac{1}{2} V_D^2 \right\}$$



Pinch off at  $V_D = V_G - V_T$

$$I_D = \frac{\mu E_0 E_f}{d_{ox}} \frac{W}{L} \left\{ (V_G - V_T)(V_G - V_T) - \frac{1}{2} (V_G - V_T)^2 \right\}$$

$$I_D = \frac{\mu E_0 E_f}{2 d_{ox}} \frac{W}{L} (V_G - V_T)^2 \quad \text{independent of } V_D!$$



# 1.3 Transistor equation

For the range  $V_D=0$  to  $V_D=V_G-V_T$

$$I_D = \frac{\mu\epsilon_0\epsilon_r}{d_{ox}} \frac{W}{L} \left\{ (V_G - V_T)(V_D) - \frac{1}{2}(V_D)^2 \right\}$$

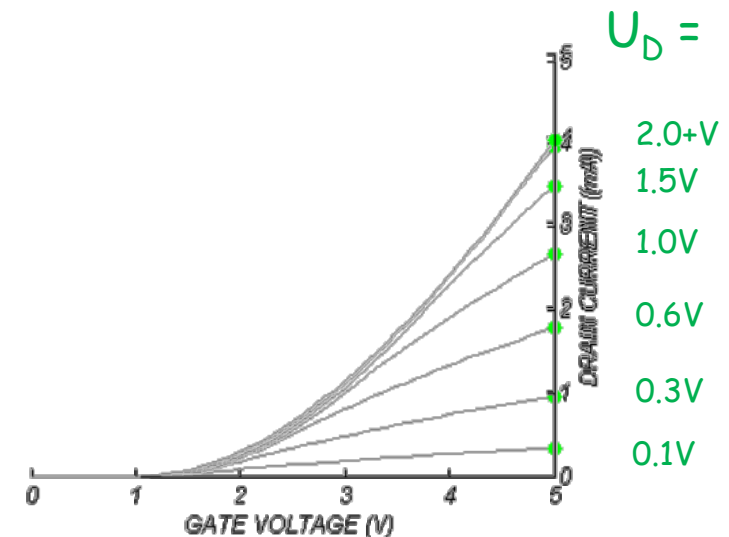
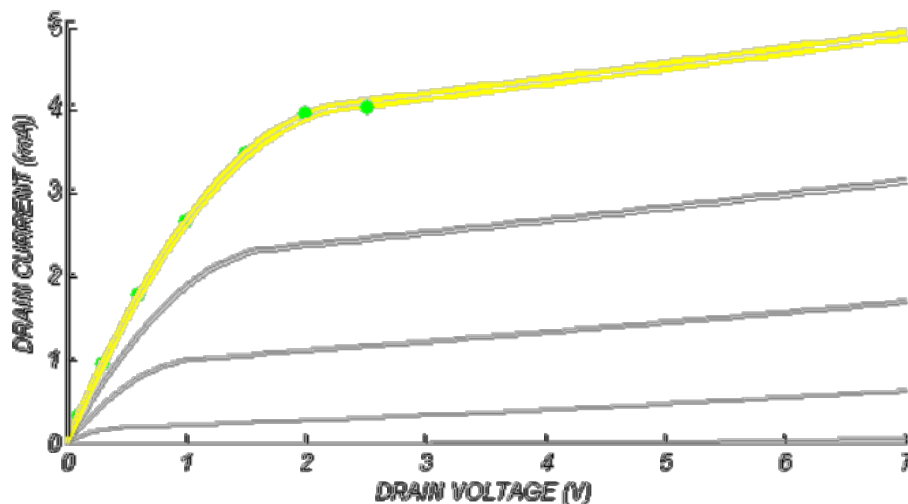
Pinch-Off at:

$$V_D = V_G - V_T$$

From there on:

$$I_{Dsat} = \frac{\mu\epsilon_0\epsilon_r}{2d_{ox}} \frac{W}{L} (V_G - V_T)^2$$

Independent of  $V_D$



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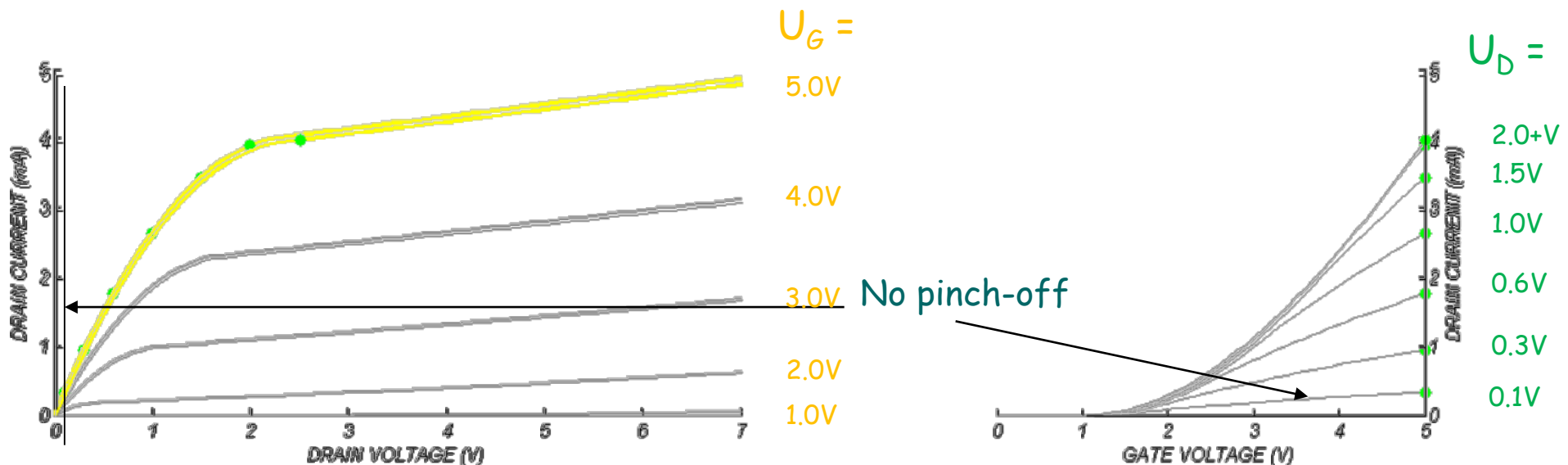
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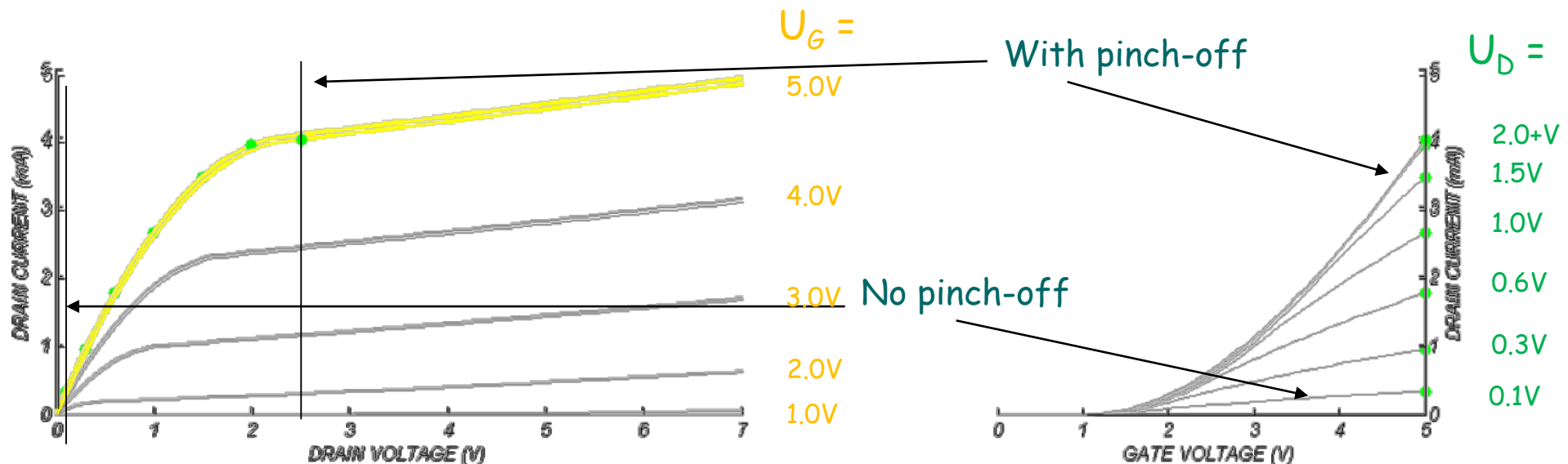
Pinch-Off at:

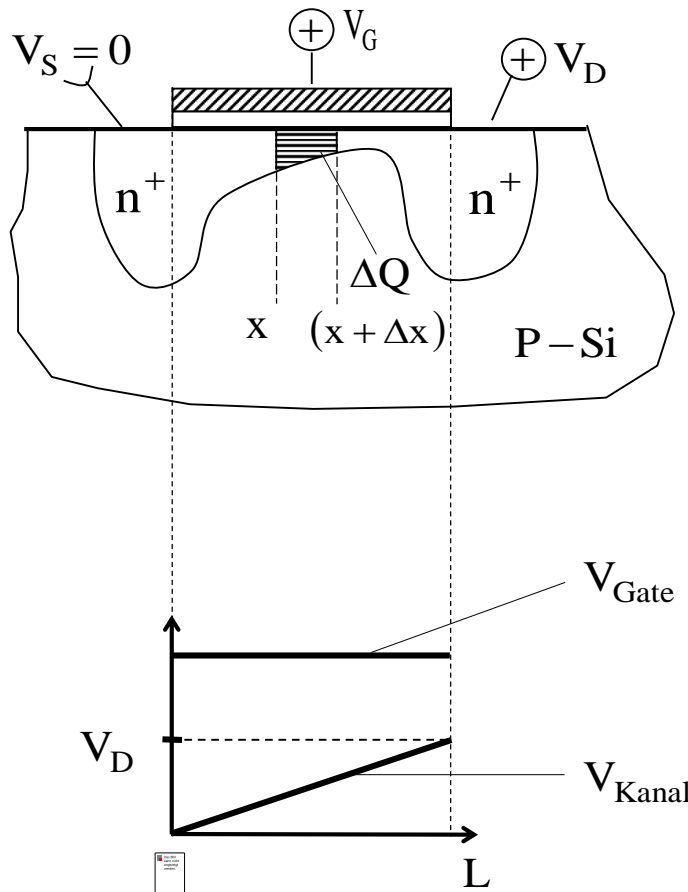
$$V_D = V_G - V_T$$

From there on:

$$I_{Dsat} = \frac{\mu\epsilon_0\epsilon_r}{2d_{ox}} \frac{W}{L} (V_G - V_T)^2$$

Independent of  $V_D$





- Gate Capacity:  $C_G = \frac{\epsilon_0 \epsilon_r W \cdot L}{d_{ox}}$
- Capacity within:  $\Delta x$   $\Delta C = C_G \frac{\Delta x}{L}$
- Charge between  $x$ ;  $(x + \Delta x)$ :  $\Delta Q = \Delta C (V_G - V(x))$
- El. Field in x-Direction:  $E = -\frac{dV}{dx}$
- Velocity of the Electrons in the channel  $\mu$ : Electron mobility  $v = -\mu \cdot E = \mu \frac{dV}{dx}$
- Charge carrier density per unit length  $\rho_x = \frac{\Delta Q}{\Delta x}$

## Derivation (2)

Current: 
$$I_D = \rho_x \cdot v = \frac{\Delta Q}{\Delta x} \cdot \mu \frac{dV}{dx} = \frac{\Delta C(V_G - V(x))}{\Delta x} \cdot \mu \frac{dV}{dx}$$

$$I_D = \frac{C_G \cdot \Delta x (V_G - V(x))}{L \cdot \Delta x} \cdot \mu \frac{dV}{dx} = \frac{C_G \cdot \mu}{L} (V_G - V(x)) \frac{dV}{dx}$$

$$I_D \cdot \int_0^L dx = \frac{C_G \cdot \mu}{L} \int_0^{V_D} (V_G - V(x)) dV = \frac{C_G \cdot \mu}{L} \cdot \left( \int_0^{V_D} V_G dV - \int_0^{V_D} V(x) dV \right)$$

$$I_D \cdot L = \frac{C_G \cdot \mu}{L} \left( V_G V_D - \frac{1}{2} V_D^2 \right) = \frac{\mu \varepsilon_0 \varepsilon_r}{d_{ox}} \frac{W \cdot L}{L} \left( V_G V_D - \frac{1}{2} V_D^2 \right)$$

So far threshold voltage  $V_T$  not considered! Therefore:  $V_G \rightarrow V_G - V_T$

$$I_D = \frac{\mu \varepsilon_0 \varepsilon_r}{d_{ox}} \frac{W}{L} \left\{ (V_G - V_T) \cdot V_D - \frac{1}{2} V_D^2 \right\}$$

Pinch off at

$$V_D = V_G - V_T$$

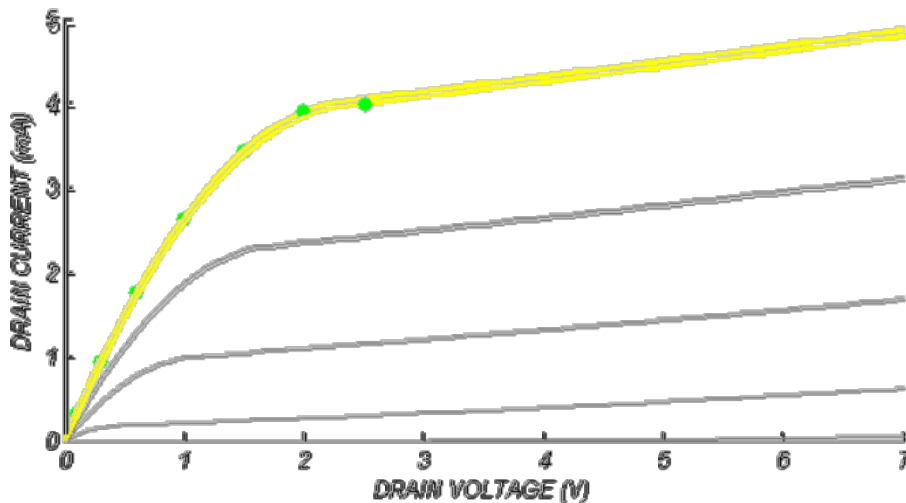
It follows

$$I_D = \frac{\mu \epsilon_0 \epsilon_r}{d_{ox}} \frac{W}{L} \left\{ (V_G - V_T)(V_G - V_T) - \frac{1}{2}(V_G - V_T)^2 \right\}$$

$$I_D = \frac{\mu \epsilon_0 \epsilon_r}{2d_{ox}} \frac{W}{L} (V_G - V_T)^2$$

Independent of

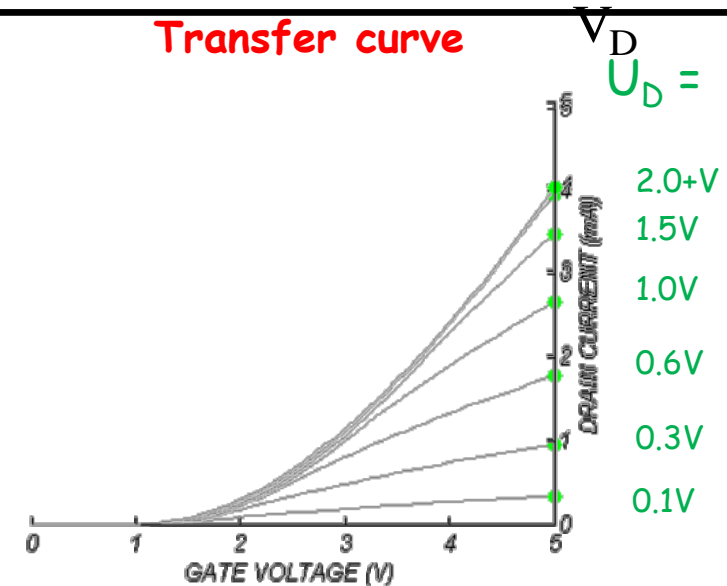
**MOSFET Characteristic**



$U_G =$

- 5.0V
- 4.0V
- 3.0V
- 2.0V
- 1.0V

**Transfer curve**



$U_D =$

- 2.0V
- 1.5V
- 1.0V
- 0.6V
- 0.3V
- 0.1V

Pinch off at

$$V_D = V_G - V_T$$

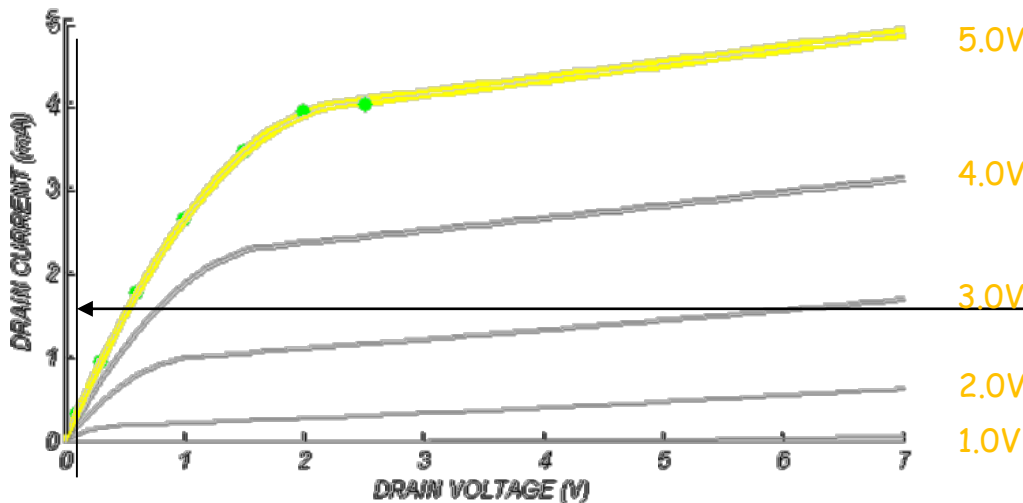
It follows

$$I_D = \frac{\mu \epsilon_0 \epsilon_r}{d_{ox}} \frac{W}{L} \left\{ (V_G - V_T)(V_G - V_T) - \frac{1}{2}(V_G - V_T)^2 \right\}$$

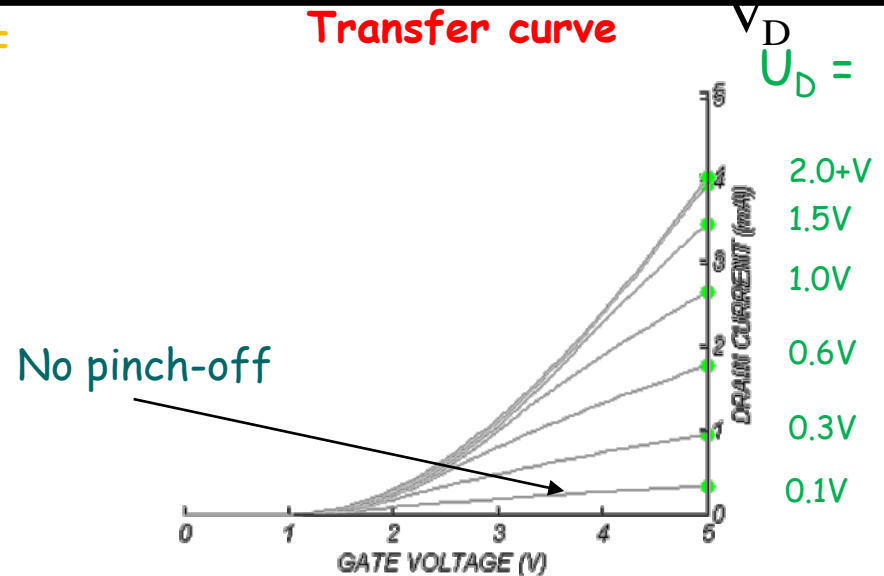
$$I_D = \frac{\mu \epsilon_0 \epsilon_r}{2d_{ox}} \frac{W}{L} (V_G - V_T)^2$$

Independent of

**MOSFET Characteristic**



**Transfer curve**



No pinch-off

Pinch off at

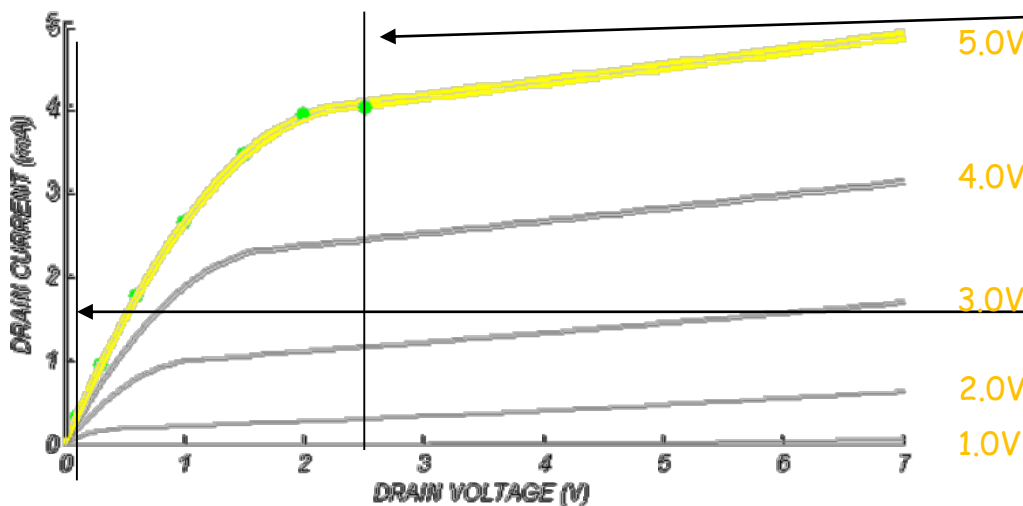
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It follows

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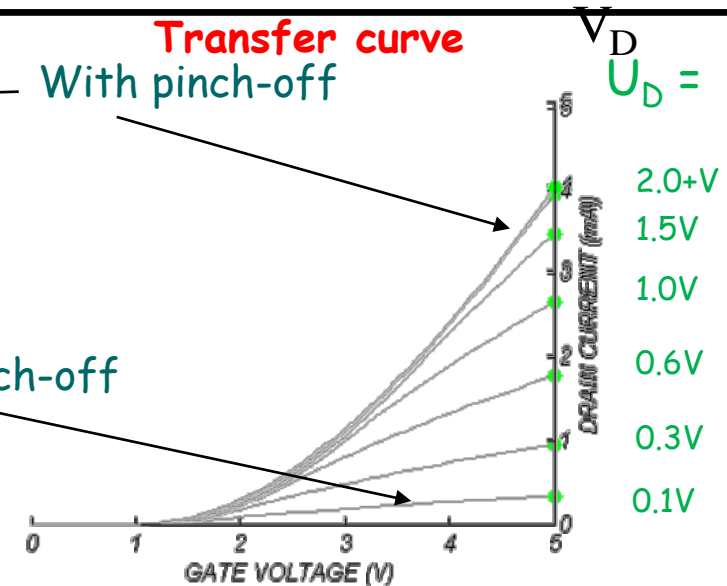
$$I_D = \frac{\mu \epsilon_0 \epsilon_r}{2d_{ox}} \frac{W}{L} (V_G - V_T)^2 \quad \text{Independent of}$$

**MOSFET Characteristic**



**Transfer curve**  
With pinch-off

No pinch-off



Pinch off at

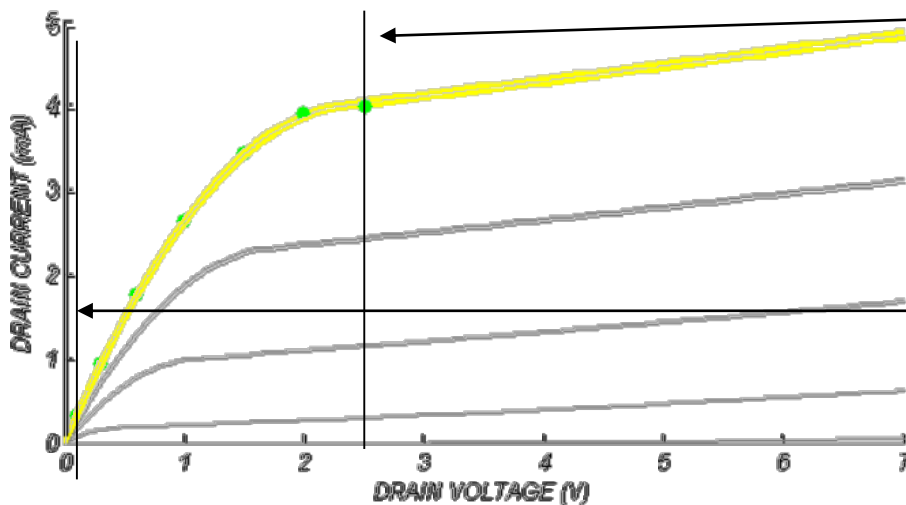
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MOSFET Characteristic



$U_G =$

5.0V

4.0V

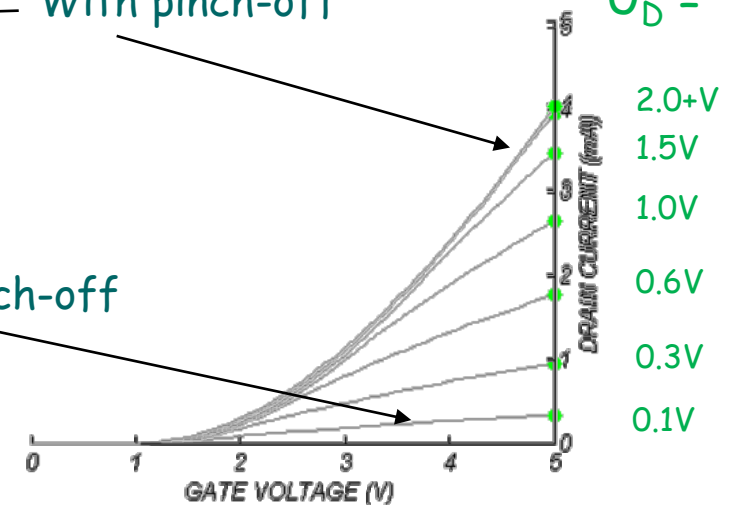
3.0V

2.0V

1.0V

No pinch-off

Transfer curve With pinch-off



$V_D = U_D =$

2.0+V

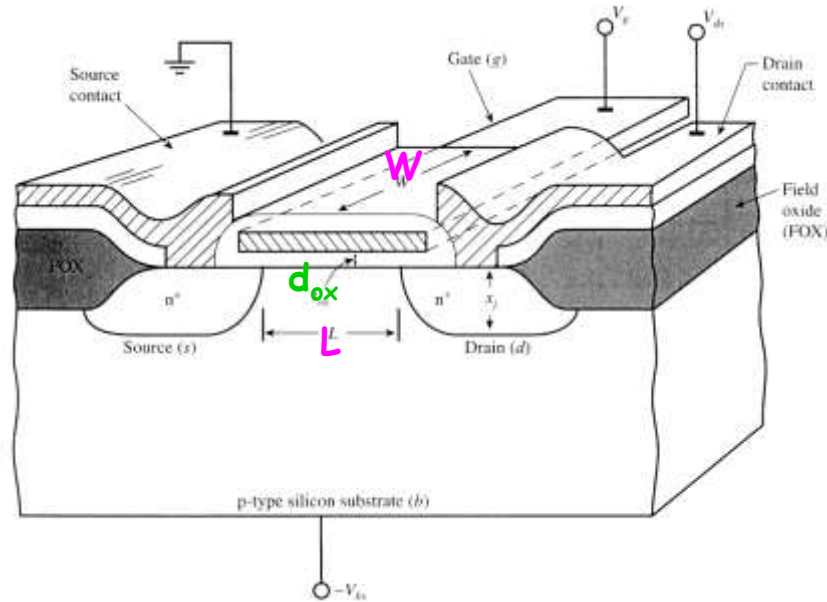
1.5V

1.0V

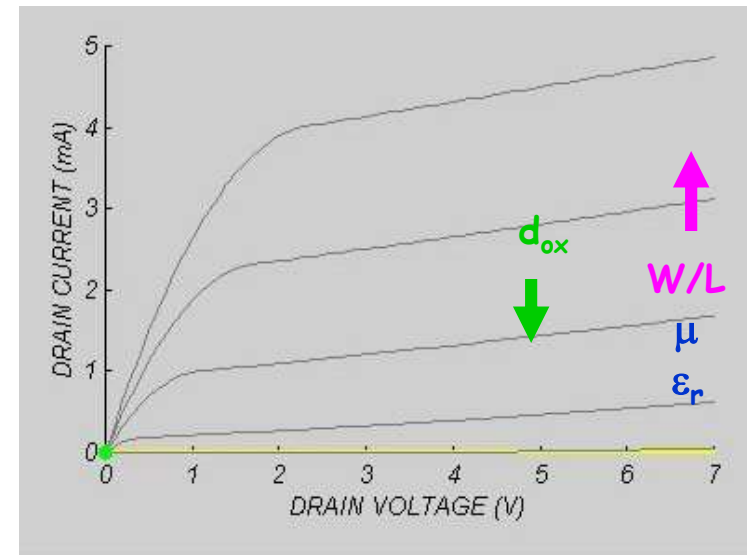
0.6V

0.3V

0.1V



## Size Effects:



$$I_D = (\mu \epsilon_0 \epsilon_r / d_{ox}) \cdot W/L \cdot ((V_G - V_T) - \frac{1}{2} V_D) \cdot V_D$$

$$V_T \sim d_{ox} \cdot N_A \text{ and Material}$$

Controlled by:

Design

Process

Material





**»Wissen schafft Brücken.«**